



Dkt. 71745 CCD

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Todd F. BISCHOFF et al.

Serial No.: 10/735,057

Group Art Unit 1755

Filed : December 11, 2003

For : METHOD FOR SUPPRESSING REACTION OF MOLTEN
METALS WITH REFRACTORY MATERIALS

INFORMATION DISCLOSURE STATEMENT

1185 Ave. of the Americas
New York, N.Y. 10036
May 20, 2004

Hon. Commissioner for Patents
P. O. BOX 1450
Alexandria, VA 22313-1450

S I R:

Attention is respectfully directed to the items of information (copies enclosed) listed on the attached form PTO-1449.

Respectfully,

Christopher C. Dunham
Christopher C. Dunham
Reg. No. 22,031
Attorney for Applicants
Tel. (212) 278-0400

I hereby certify that this paper is being deposited this date with the U.S. Postal Service as first class mail addressed to Assistant Commissioner for Patents, P. O. BOX 1450 Alexandria, VA 22313-1450

Christopher C. Dunham
Christopher C. Dunham, Reg. No. 22,031

Date: MAY 20, 2004

Form PTO-1449 (Rev.7-80)	U.S. Department of Commerce Patent & Trademark Office	ATTY. DOCKET NO. 2528/1745 CCD	SERIAL NO. 10/735,057
LIST OF REFERENCES CITED BY APPLICANT (Use several sheets if necessary)		APPLICANT BISCHOFF, Todd et al.	
		FILING DATE: December 11, 2003	GROUP



U.S. PATENT DOCUMENTS

*Examiner Initial	Codes	Document Number	Date	Name	Class	Subclass	Filing Date
	B1	3,078,173	02/19/1963	Dolph	106	62	11/08/1960
	B1	4,622,070	11/11/1986	Sakurai et al.	106	38.22	11/14/1984
	B1	4,690,867	09/01/1987	Yamamoto et al.	428	367	03/31/1986
	B1	4,762,811	08/09/1988	Vayda et al.	501	124	01/27/1987
	B1	4,992,395	02/12/1991	Dulberg et al.	501	95	04/28/1989
	B1	5,039,634	08/13/1991	Dulberg et al.	501	95	06/04/1990
	B1	6,008,152	12/28/1999	Guillo et al.	501	54	07/24/1996
	B1	6,066,289	05/23/2000	Eckert	266	235	04/14/1998
	B2	6,548,436	04/15/2003	Prior et al.	501	125	04/15/2002

FOREIGN PATENT DOCUMENTS

	Kind Codes	Document number	Date	Country	Class	Subclass	Translation
	B1	580,916	09/24/1946	Great Britain			

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

Examiner	Date considered
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	